

Attorney Docket No. P121-US

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: Dmitri Simonian, et al.

Art Unit: Not Yet Assigned

Serial No.: Not Yet Assigned

Examiner: Not Yet Assigned

Filed: Herewith

For: **SURFACE PROCESSES IN FABRICATIONS OF MICROSTRUCTURES**

**INFORMATION DISCLOSURE STATEMENT**  
**PURSUANT TO 37 CFR 1.97(b)**

Commissioner for Patents  
Alexandria, VA 22313-145

Sir:

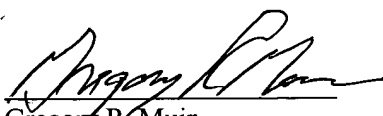
The attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached PTO Form 1449. Copies of the cited references are enclosed.

No fee or certification is required in connection with this Information Disclosure Statement, since it is being submitted prior to the last of (1) issuance of a first official action on the merits and (2) expiration of the three month period following filing of the above-captioned application.

The above information is presented so that the Patent and Trademark Office can determine any materiality thereof to the claimed invention. It is respectfully requested that the information be considered during the prosecution of this application and that the cited documents be listed on the front page of any patent issuing from this application.

The Patent Office is authorized to charge our Deposit Account No. 501516 for any fee which it deems to be required to effect consideration of this statement.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "Gregory R. Muir", written over a horizontal line.

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<b>INFORMATION DISCLOSURE CITATION</b>  <b>PTO-1449</b>		ATTY. DOCKET NO. P121-US		SERIAL NO. Not Yet Assigned			
		APPLICANT Dima Simonia					
		FILING DATE Herewith		GROUP Not Yet Assigned			
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	6,300,294	10/09/01	Robbins, et al.				
	6,259,551	07/10/01	Jabobs				
	5,936,758	08/10/99	Fisher, et al.				
	5,411,769	05/02/95	Hornbeck				
	5,939,785	08/17/99	Klonis, et al.				
<b>FOREIGN PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
						<input type="checkbox"/>	<input type="checkbox"/>
						<input type="checkbox"/>	<input type="checkbox"/>
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
	Uthara Srinivasan, et al., ALKYLTRICHLOROSILANE-BASED SELF-ASSEMBLED MONOLAYER FILMS FOR STRICTION REDUCTION IN SILICON MICROMACHINES., Journal of Microelectromechanical Systems, Vol. 7, No. 2 June 1998, Pgs 252-260.						
	H. Zarrad, et al., OPTIMIZATION OF LUBRICANTS FOR SILICA MICROMOTORS., Sensors and Actuators A 46-47 (1995), Pgs 598-600.						
	Uthara Srinivasan, et al., 1997 INTERNATIONAL CONFERENCE ON SOLID-STATE SENSORS AND ACTUATORS., Transducers 97 Chicago, June 16-19, 1997.						
	Roya Maboudian, et al., STRICTION REDUCTION PROCESSES FOR SURFACE MICROMACHINES., Tribology Letters 3 (1997), Pgs 215-221.						
	K. Komvopoulos, SURFACE ENGINEERING AND MICROTRIBOLOGY FOR MICROELECTROMECHANICAL SYSTEMS., Wear 200 (1996), Pgs 305-327.						
	W. Robert Ashurst, WAFER LEVEL ANTI-STICTION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.						
	H. Zarrad, et al., THE USE OF LONG-CHAIN MOLECULES FOR THE LUBRICATION OF MICROMECHANISMS., Journal of Micromech. Microeng. 3 (1993), Pgs 222-224.						
EXAMINER			DATE CONSIDERED				

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.